IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

#5 6.6.02

In re PATENT APPLICATION

GUI et al.

Application No.: 10/043,271

Filed: January 14, 2002

Title: LITHOGRAPHIC APPARATUS

Group Art Unit: 2851

Examiner: Unknown

Atty Dkt <u>81468/290598</u>

C# M#

May 31, 2002

INFORMATION DISCLOSURE STATEMENT

Assistant Commissioner for Patents Washington, D.C. 20231

Sir:

Attached is Form PTO-1449 listing the enclosed documents.

Should a first action on the merits have been issued on the same day or before this Information Disclosure Statement is filed, please accept this Information Disclosure Statement under Rule 97(c) and charge the requisite Rule 17(p) fee to our Deposit Account No. 03-3975, under Order No. 81468/290598 and proceed to consider this Information Disclosure Statement.

This IDS is intended to be in full compliance with the rules, but should the Examiner find any part of its required content to have been omitted, promptotice to that effect is earnestly solicited, along with additional time under Rule 97(f) to enable Applicant to comply fully.

Consideration of the foregoing and enclosures plus the return of a py of the enclosed Form PTO-1449 with the Examiner's initials in the left column per MEP 009 are earnestly solicited along with an early action on the merits.

By: (

Respectfully submitted,

PILLSBURY WINTHROP LLP

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*EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.